



#4 S/H COVER 10/19/00

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| Form 1449 (Modified) Information Disclosure Statement By Applicant (Use Several Sheets if Necessary) | Atty. Docket No. | Application No.: |
| | NVIDP013/P000176 | 09/535,045 |
| | Applicant: | |
| | Donovan et al. | |
| | Filing Date: | Group Art Unit: |
| | 3/24/00 | 2787 |

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U.S. Patent Documents

| Examiner Initial | No. | Patent No. | Date | Patentee | Class | Sub-class | Filing Date |
|------------------|-----|------------|------|----------|-------|-----------|-------------|
| | A | | | | | | |
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Foreign Patent or Published Foreign Patent Application

| Examiner Initial | No. | Document No. | Publication Date | Country or Patent Office | Class | Sub-class | Translation | |
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Other Documents

| Examiner Initial | No. | Author, Title, Date, Place (e.g. Journal) of Publication |
|------------------------|-----|---|
| S.C. | R | Lance Williams; "Pyramidal Parametrics"; July 1983; Computer Graphics, Vol. 17. No. 3 Computer Graphics Laboratory, New York Institute of Technology, Old Westbury, N.Y.; pp 1-11 |
| S.W. | S | James F. Blinn et al., "Texture and Reflection in Computer Generated Images"; October 1976; Graphics and Image Processing; Association for Computing Machinery, Inc. pp 542-547. |
| S.W. | T | Ned Greene, New York Institute of Technology; "Environment Mapping and Other Applications of World Projections"; November 1986; The Institute of Electrical and Electronics Engineers Inc. Computer Society; pp 21-29 |
| Examiner Scott Wallace | | Date Considered 03/22/02 |

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.